

IN THE CLAIMS

The following is a complete listing of the claims, and replaces all earlier versions and listings.

1. (Canceled)

2. (Cancelled)

3. (Currently Amended) A method of manufacturing an electronic device [[as claimed in claim 1]], comprising the steps of:

moving, relative to each other, a droplet ejecting portion of an ink jet device and a substrate, to which droplets are to be ejected, in a direction along a droplet-receiving surface of the substrate, and detecting a distance between the droplet ejecting portion and the droplet-receiving surface of the substrate; and

ejecting toward a plurality of portions separated mutually on the substrate at plural times at a predetermined time interval the droplets of a liquid containing material for forming the electronic device, wherein the predetermined time interval is controlled based on a result of the detecting, and

wherein the detecting of the distance includes a step of measuring the distances between the ejecting portion and the plurality of portions separated mutually on the substrate.

4. (Currently Amended) A method of manufacturing an electronic device, ~~as claimed in claim, 1~~ comprising the steps of:
moving, relative to each other, a droplet ejecting portion of an ink jet device and a substrate, to which droplets are to be ejected, in a direction along a droplet-receiving surface of the substrate, and detecting a distance between the droplet ejecting portion and the droplet-receiving surface of the substrate; and
ejecting toward a plurality of portions separated mutually on the substrate at plural times at a predetermined time interval the droplets of a liquid containing material for forming the electronic device, wherein the predetermined time interval is controlled based on a result of the detecting, and
wherein the detecting of the distance includes a step of measuring a distance between the ejecting portion and ~~[[one or]]~~ some of the plurality of portions separated mutually on the substrate.

5.-17. (Cancelled)

18. (Currently Amended) A method of manufacturing an electronic device as claimed in claim ~~[[1]]~~ 3 or 4, wherein the ink jet device is of a type that imparts thermal energy to the liquid to produce a bubble, thereby to eject a droplet.

19. (Currently Amended) A method of manufacturing an electronic device as claimed in claim [[1]] 3 or 4, wherein the ink jet device is of a type that ejects the droplets by means of a piezo-electric element.

20. (Canceled)

21. (Cancelled)

22. (Currently Amended) A method of manufacturing an electron source [[as claimed in claim 20]], having a plurality of electron-emitting devices, comprising the steps of:

moving, relative to each other, a droplet ejecting portion of an ink jet device and a substrate, to which droplets are to be ejected, in a direction along a droplet-receiving surface of the substrate;

detecting a distance between the droplet ejecting portion and the droplet-receiving surface of the substrate; and

ejecting to a plurality of portions separated mutually on the substrate at plural times at a predetermined time interval the droplets of a liquid containing material for forming a conductive member of the electron-emitting devices, wherein the predetermined time interval is determined based on a result of the detecting, and

wherein the detecting of the distance includes a step of measuring the distances between the ejecting portion and [[and]] the plurality of portions separated mutually on the substrate.

23. (Currently Amended) A method of manufacturing an electron source [[as claimed in claim 20]], having a plurality of electron-emitting devices,
comprising the steps of:

moving, relative to each other, a droplet ejecting portion of an ink jet device
and a substrate, to which droplets are to be ejected, in a direction along a droplet-receiving
surface of the substrate;

detecting a distance between the ejecting portion and the droplet-receiving
surface of the substrate; and

ejecting to a plurality of portions separated mutually on the substrate at
plural times at a predetermined time interval the droplets of a liquid containing material for
forming a conductive member of the electron-emitting devices, wherein the predetermined
time interval is determined based on a result of the detecting, and

wherein the detecting of the distance includes a step of measuring a distance between the ejecting portion and [[one or]] some of the plurality of portions separated mutually on the substrate.

24. - 70. (Cancelled)

71. (Currently Amended) A method of manufacturing an electron source as claimed in claim [[20]] 22 or 23, wherein the ink jet device is of a type that imparts thermal energy to the liquid to produce a bubble, thereby to eject a droplet.

72. (Currently Amended) A method of manufacturing an electron source as claimed in claim [[20]] 22 or 23, wherein the ink jet device is of a type that ejects the droplets by means of a piezo-electric element.

73. (Currently Amended) A method of manufacturing an image forming apparatus having an electron source and an image forming member onto which electrons are irradiated from the electron source, wherein the electron source is one that has been manufactured by a method as claimed in claim [[20]] 22 or 23.

74. - 98. (Cancelled)

99. (New) A method of manufacturing an electronic device [[as claimed in claim 7]], comprising the steps of:

moving, relative to each other, a droplet ejecting portion of an ink jet device and a substrate, to which droplets are to be ejected, in a direction along a droplet-receiving surface of the substrate, while detecting a distance between the ejection portion and the droplet-receiving surface of the substrate; and

ejecting toward a plurality of portions separated mutually on the substrate at plural times at a predetermined time interval the droplets of a liquid containing material for forming the electronic device, wherein the predetermined time interval is controlled based on a result of the detecting, and

wherein the detecting of the distance includes a step of measuring the distance between the ejecting portion and the plurality of portions separated mutually on the substrate.

100. (New) A method of manufacturing an electronic device [[as claimed in claim 7]], comprising the steps of:

moving, relative to each other, a droplet ejecting portion of an ink jet device and a substrate, to which droplets are to be ejected, in a direction along a droplet-receiving surface of the substrate, while detecting a distance between the ejection portion and the droplet-receiving surface of the substrate; and

ejecting toward a plurality of portions separated mutually on the substrate at plural times at a predetermined time interval the droplets of a liquid containing material for forming the electronic device, wherein the predetermined time interval is controlled based on a result of the detecting, and

wherein the detecting of the distance includes a step of measuring a distance between the ejecting portion and [[one or]] some of the plurality of portions separated mutually on the substrate.

101. (Canceled)

102. (Currently Amended) A method of manufacturing an electron source [[as claimed in claim 26]], having a plurality of electron-emitting devices, comprising the steps of:

moving, relative to each other, a droplet ejection portion on an ink jet device and a substrate, to which droplets are to be ejected, in a direction along a droplet-receiving surface of the substrate, while detecting a distance between the ejecting portion and the droplet-receiving surface of the substrate; and

ejecting to a plurality of portions separated mutually on the substrate at plural times at a predetermined time interval the droplets of a liquid containing material for forming the electron-emitting devices, wherein the predetermined time interval is controlled based on a result of the detecting, and

wherein the detecting of the distance includes a step of measuring the distances between the ejecting portion and the plurality of portions separated mutually on the substrate.

103. (New) A method of manufacturing an electron source [[as claimed in claim 26]], having a plurality of electron-emitting devices, comprising the steps of:

moving, relative to each other, a droplet ejection portion on an ink jet device and a substrate, to which droplets are to be ejected, in a direction along a droplet-receiving

surface of the substrate, while detecting a distance between the ejecting portion and the droplet-receiving surface of the substrate; and

ejecting to a plurality of portions separated mutually on the substrate at plural times at a predetermined time interval the droplets of a liquid containing material for forming the electron-emitting devices, wherein the predetermined time interval is controlled based on a result of the detecting, and

wherein the detecting of the distance includes a step of measuring a distance between the ejecting portion and [[one or]] some of the plurality of portions separated mutually on the substrate.

104. (Canceled)

105. (New) A method of manufacturing an image forming apparatus having an electron source and an image forming member onto which electrons are irradiated from the electron source, wherein the electron source is manufactured by a method as claimed in claim [[26]] 102 or 103.

106. (New) A method of manufacturing an electronic device as claimed in claim 99 or 100, wherein the ink jet device ejects the droplets by applying thermal energy to the liquid to generate a bubble in the liquid.

107. (New) A method of manufacturing an electronic device as claimed in claim 99 or 100, wherein the ink jet device ejects the droplets by means of a piezo-electric element.

108. (New) A method of manufacturing an electron source as claimed in claim 102 or 103, wherein the ink jet device ejects the droplets by applying thermal energy to the liquid to generate a bubble in the liquid.

109. (New) A method of manufacturing an electron source as claimed in claim 102 or 103, wherein the ink jet device ejects the droplets by means of a piezo-electric element.